

Alexandre Bes

List of Publications by Year in descending order

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papers

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1163117

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22
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325
citing authors

#	ARTICLE	IF	CITATIONS
1	X-ray beam induced current analysis of CVD diamond detectors in the perspective of a beam tagging hodoscope development for hadrontherapy on-line monitoring. <i>Diamond and Related Materials</i> , 2021, 112, 108236.	3.9	2
2	A Study of the Radiation Tolerance of CVD Diamond to 70 MeV Protons, Fast Neutrons and 200 MeV Pions. <i>Sensors</i> , 2020, 20, 6648.	3.8	10
3	Three-phase metal-insulator transition and structural alternative for a VO ₂ film epitaxially grown on Al ₂ O ₃ (0001). <i>Journal of Applied Physics</i> , 2019, 126, 165306.	2.5	5
4	Boron-10 conversion layer for ultra-cold neutron detection. <i>Journal of Instrumentation</i> , 2019, 14, P09003-P09003.	1.2	4
5	A study of the radiation tolerance of poly-crystalline and single-crystalline CVD diamond to 800 MeV and 24 GeV protons. <i>Journal Physics D: Applied Physics</i> , 2019, 52, 465103.	2.8	11
6	Sulfur: an alternative to mercury for UV emission in low-pressure low-power fluorescent discharges. <i>Journal Physics D: Applied Physics</i> , 2019, 52, 32LT02.	2.8	2
7	Diamond detectors for high energy physics experiments. <i>Journal of Instrumentation</i> , 2018, 13, C01029-C01029.	1.2	42
8	A Better Understanding of the Very Low-Pressure Plasma Polymerization of Aniline by Optical Emission Spectroscopy Analysis. <i>Plasma Chemistry and Plasma Processing</i> , 2018, 38, 887-902.	2.4	6
9	Oxygen plasma etching of hydrocarbon-like polymers: Part II experimental validation. <i>Plasma Processes and Polymers</i> , 2018, 15, 1800037.	3.0	1
10	Oxygen plasma etching of hydrocarbon-like polymers: Part I Modeling. <i>Plasma Processes and Polymers</i> , 2018, 15, 1800038.	3.0	4
11	Dehydrogenation process and thermal stability of Mg-Ti-H films in-situ hydrogenated by microwave reactive plasma-assisted co-sputtering technique. <i>Journal of Alloys and Compounds</i> , 2018, 768, 157-165.	5.5	4
12	Morphology and microstructure of Mg-Ti-H films deposited by microwave plasma-assisted co-sputtering. <i>Journal of Alloys and Compounds</i> , 2017, 708, 489-499.	5.5	10
13	Nanotexturing of plasma-polymer thin films using argon plasma treatment. <i>Surface and Coatings Technology</i> , 2017, 330, 196-203.	4.8	7
14	Characterization of X-ray gas attenuator plasmas by optical emission and tunable laser absorption spectroscopies. <i>Journal of Synchrotron Radiation</i> , 2017, 24, 1195-1208.	2.4	1
15	Investigation of Diffusion Barrier Layers for Bi-Doped Mg ₂ (Si,Ge) Thermoelectric Legs. <i>Journal of Electronic Materials</i> , 2016, 45, 5570-5581.	2.2	1
16	An open-ended coaxial plasma source with extended operating parameters: plasma impedance, coupling and energy efficiency. <i>Plasma Sources Science and Technology</i> , 2014, 23, 064006.	3.1	5
17	MgH ₂ thin films deposited by one-step reactive plasma sputtering. <i>International Journal of Hydrogen Energy</i> , 2014, 39, 17718-17725.	7.1	17
18	Multi-dipolar microwave plasmas and their application to negative ion production. <i>Physics of Plasmas</i> , 2013, 20, .	1.9	39

#	ARTICLE	IF	CITATIONS
19	Deposition of thin films of $Mg_{2-1-x}Si_{1+x}Sn_x$ solid solution by plasma-assisted co-sputtering. Journal of Alloys and Compounds, 2012, 538, 73-78.	5.5	15
20	High deposition rates of uniform films in tetramethylsilane-based plasmas generated by elementary microwave sources in matrix configuration. Surface and Coatings Technology, 2009, 203, 2343-2349.	4.8	7
21	Production of H^+ ions by Surface Mechanisms in Cs-free Multi-dipolar Microwave Plasma. , 2009, , .		6
22	Characterization of high density matrix microwave argon plasmas by laser absorption and electric probe diagnostics. Journal Physics D: Applied Physics, 2007, 40, 5177-5186.	2.8	25